

<b>APPLICANT'S ART CITATION</b> (Use several sheets if necessary)		Application		OFGS File No. <b>304579000</b> 12/1/99 28		
		Applicant <b>Alexander Apodonski et al</b>				
		Filing Date		Group Art Unit		
<b>U.S. PATENT DOCUMENTS</b> (not submitted for applications filed after 6/30/03)						
Examiner Initial	Document Number	Date MM-YYYY	Name	Class	Sub-class	Filing Date If Appropriate
	US-5,734,503	03-1998	Szipócs et al	359	584	
<b>FOREIGN PATENT DOCUMENTS</b>						
	Document Number	Date MM-YYYY	Country	Class	Sub-class	Translation Yes      No
	WO 01/05000 A	01-2001	WIPO			abstract
	AT 405 992 B	11-1999	Austria			abstract
	AT 411411	11-2003	Austria			abstract
<b>OTHER DOCUMENTS</b> (Including Author, Title, Date, Pertinent Pages, Etc.)						
		Cho S H et al: "Generation of 90-NJ Pulses with a 4-MHZ Repetition-Rate Kerr-Lens Mode-Locked TI: AL 203 Laser Operating with Net Positive and Negative Intracavity Dispersion: Optic Letters, Optical Society of America, Washington, US, vol. 26, no. 8, 15 April 2001, pages 560-562, ISSN: 0146-9592 cited in the application				
		Matuschek N. et al: "Analytical design of double-chirped mirrors with custome-tailored dispersion characteristics" IEEE Journal of Quantum Electronics, IEEE Inc. New York, US, Vol. 35, no. 2. February 1999 (1999-02), Pages 129-137, XP002109637 ISSN: 0018-9197				
		Stingl A et al: Generation of 11-FS Pulses from a TI: Sapphire Laser without the use of Prisms" Optics letters, optical society of america, Washington, US, vol. 19, no. 3, 1 February 1994 (1994-02-01), pages 204-206, XP000424365 ISSN: 0146-9592				
		D. Herriott et al., "off-Axis Paths in Spherical Mirror Interferometers". Applied Optics, April 1964, Vol 3, No. 4, pp 523-526				
		A. Poppe et al., "A Sub-10 fs, 2.5-MW Ti: Sapphire Oscillatore", Ultrafast Optics 1999, pp. 154-157, Ascona, Switzerland				
		International Search Report PCT/AT2004/000336 dated 30 November 2004				
Examiner		Date Considered				
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